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(54) Title: MODULAR ABATEMENT APPARATUS

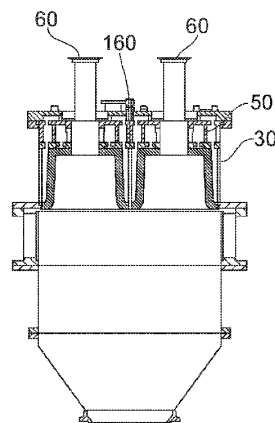


FIG. 1 (C)

(57) Abstract: A modular abatement apparatus and a method are disclosed. The modular abatement apparatus is for abatement of an effluent stream from a semiconductor processing tool and comprises: a housing defining a common housing chamber; a plurality of combustion chamber modules positionable within the common housing chamber for treating the effluent stream, each combustion chamber module containing a foram incus sleeve defining a combustion chamber there-within. In this way, multiple combustion chambers may be provided within a single, common housing, each of which may be configured to treat a particular effluent stream flow. Accordingly, the number of combustion chambers can be selected to match the different types and flowrates of the effluent stream expected from any particular processing tool. This provides an architecture which is readily scalable to suit the needs of different effluent gas stream types and flowrates while retaining a common housing which may interface with upstream and downstream components.

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